

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the Application of:

Keum Joo LEE, et al.

Art Unit: 1746

Serial No. 09/955,126

Examiner: Michael Komakov

Filed: September 19, 2001

Confirmation No. 8415

For: METHOD OF CLEANING  
DAMAGED LAYERS AND  
POLYMER RESIDUE FROM  
SEMICONDUCTOR DEVICE

Atty. Docket No. 259/011

**AMENDMENT UNDER 37 C.F.R. § 1.111***(supplemental)*Commissioner for Patents  
United States Patent and Trademark Office  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**INTRODUCTORY COMMENTS**

Further to a telephone interview with the Examiner conducted on May 25, 2004, the following amendments and remarks are respectfully submitted in connection with the above-identified application:

**Amendments to the Specification** begin on page 2 of this paper.

**Amendments to the Claims** are reflected in a listing of claims, which begins on page 3 of this paper.

**Remarks** begin on page 10 of this paper.